

Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 09712-330001	Application No. 10/616,504
<b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary)		Applicant Henry A. Hill	
		Filing Date July 8, 2003	Group Art Unit 2877

## U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
PJC	AA	4,413,908	11/1983	Abrams et al.	1	1	
	AB	4,948,254	08/1990	Ishida	1	1	
	AC	5,151,749	09/29/1992	Tanimoto et al.	1	1	
	AD	5,249,016	9/1993	Tanaka, Hiroshi	1	1	
	AE	5,331,400	07/1994	Wilkening et al.	1	1	
	AF	5,404,222	04/1995	Lis	1	1	
	AG	5,432,603	07/1995	Sentoku et al.	1	1	
	AH	5,483,343	01/1996	Iwamoto et al.	1	1	
	AI	5,491,550	02/13/1996	Dabbs	1	1	
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	AK	5,724,136	03/03/1998	Zanoni	1	1	
	AL	5,757,160	05/26/1998	Dreuzer	1	1	
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	AN	5,790,253	08/04/1998	Kamiya	1	1	
	AO	5,850,291	12/1998	Tsutsui, Shinji	1	1	
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	AQ	5,969,800	10/1999	Makinouchi	1	1	
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	AS	6,020,964	02/01/2000	Loopstra et al.	1	1	
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	AX	6,181,420	01/2001	Badami et al.	1	1	
	AY	6,201,609	03/2001	Hill et al.	1	1	
	AZ	6,271,923	08/07/2001	Hill	1	1	
PJC	AAA	6,304,318	10/16/2001	Matsumoto	1	1	

Examiner Signature <b>PATRICK CONNOLLY</b>	Date Considered <b>03.31.2005</b>
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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**U.S. Patent Documents**

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
PJC	ABB	6,313,918	11/06/2001	Hill et al.			
PJC	ACC	6,687,013	02/2004	Isshiki et al.			
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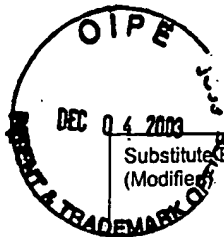
**Foreign Patent Documents or Published Foreign Patent Applications**

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
PJC	AGG	JP 7-351078	12/1995	Japan (Abstract Only)				
PJC	AHH	JP 8-117083	04/1996	Japan (Abstract Only)				
PJC	AII	JP 10-260009	09/29/1998	Japan (with Abstract)				X
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**Other Documents (include Author, Title, Date, and Place of Publication)**

Examiner Initial	Desig. ID	Document
PJC	AKK	Badami V.G. et al., "Investigation of Nonlinearity in High Accuracy Heterodyne Laser Interferometry," 1997 PROCEEDINGS, Vol. 16, pp. 153-156.
PJC	ALL	Bennett, S.J. <u>Optics Communications</u> , 4:6, pp. 428-430, 1972
PJC	AMM	Bobroff, N., "Recent Advances in Displacement Measuring Interferometry," MEASUREMENT SCIENCE & TECHNOLOGY, Vol. 4, No. 9, September 1993, pp. 907-926.
PJC	ANN	Hines, B. et al., "Sub-Nanometer Laser Metrology - Some Techniques and Models," JET PROPULSION LABORATORY, CALIFORNIA INSTITUTE OF TECHNOLOGY, pp. 1195-1204.
PJC	AOO	Oka K. et al., "Polarization Heterodyne Interferometry Using Another Local Oscillator Beam," OPTICS COMMUNICATIONS, 92 (1992), 1-5.
PJC	APP	Wu, C.M. et al., "Analytical Modeling of the Periodic Nonlinearity in Heterodyne Interferometry," APPLIED OPTICS, Vol. 37, No. 28, 1 October 1998, pp. 6696-6700.
	AQQ	

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Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
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	AB						
	AC						
	AD						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclasses	Translation	
							Yes	No
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	AI							

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
<i>PJC</i>	AJ	Norman Bobroff, "Residual errors in laser interferometry from air turbulence and nonlinearity", <u>Applied Optics</u> , Vol. 26, No. 13, pp. 2676-2682
<i>PJC</i>	AK	Mitsuru Tanaka, et al., "Linear Interpolation of Periodic Error in a Heterodyne Laser Interferometer at Subnanometer Levels", <u>IEEE Transactions on Instrumentation and Measurement</u> , Vol. 38, No. 2, pp. pp. 553-554 (April 1989)
<i>PJC</i>	AL	Chien-Ming Wu et al., "Analytical modeling of the periodic nonlinearity in heterodyne interferometry", <u>Applied Optics</u> , Vol. 37, No. 28, pp. 6696-6700 (October 1, 1998)
<i>PJC</i>	AM	Chien-Ming Wu et al., "Nonlinearity in measurements of length by optical interferometry", <u>Measurement Science and Technology</u> , Vol. 7, No. 1, pp. 62-68 (January 1996)
	AN	
	AO	

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